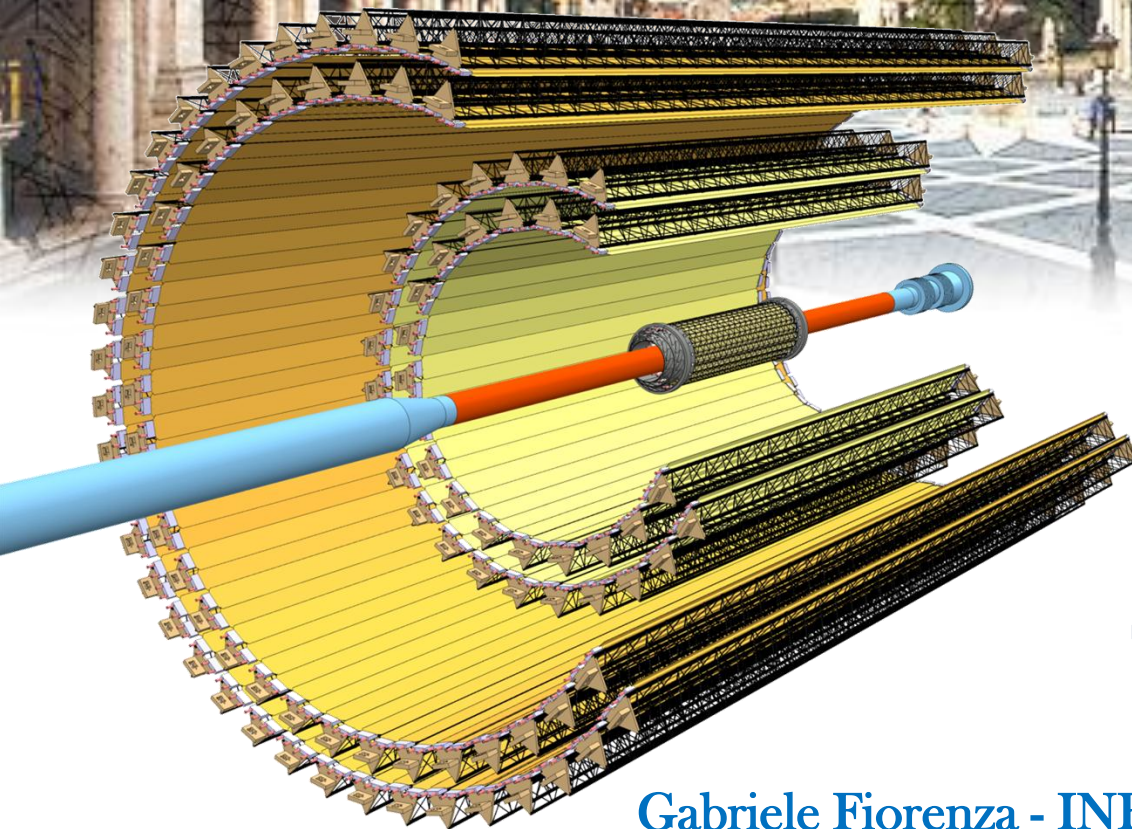
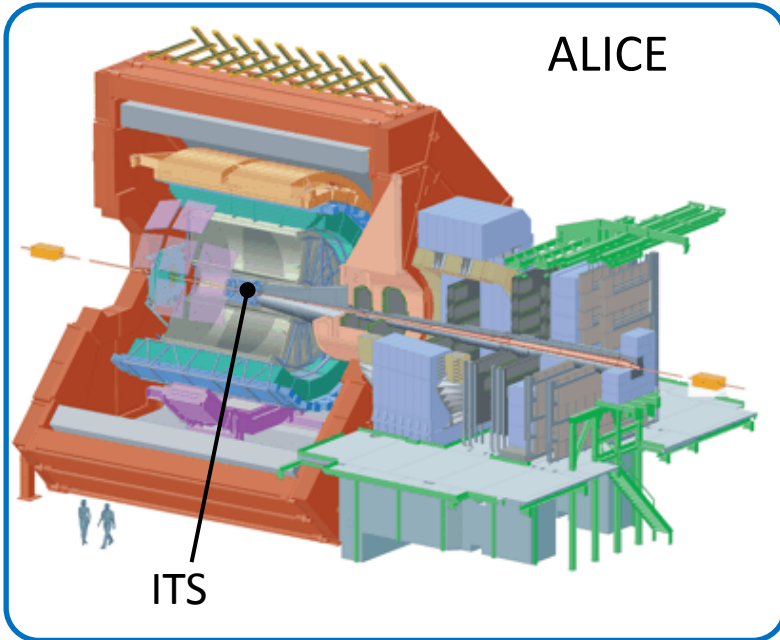


101° CONGRESSO DELLA SOCIETÀ ITALIANA DI FISICA



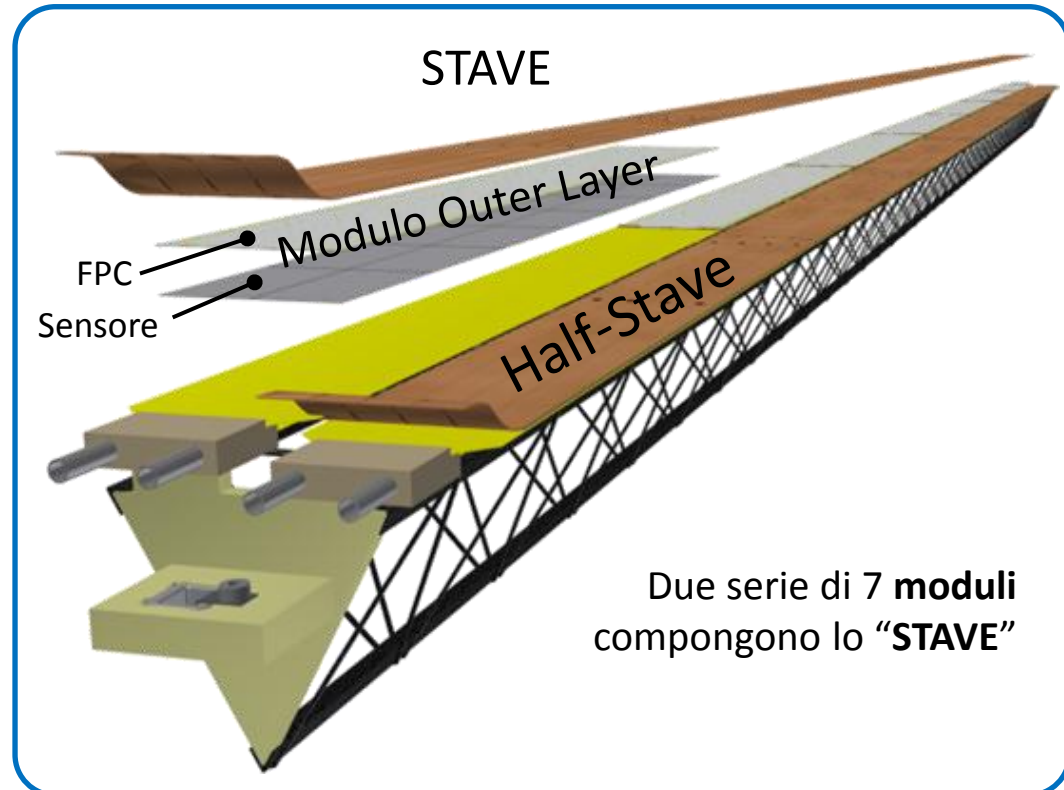
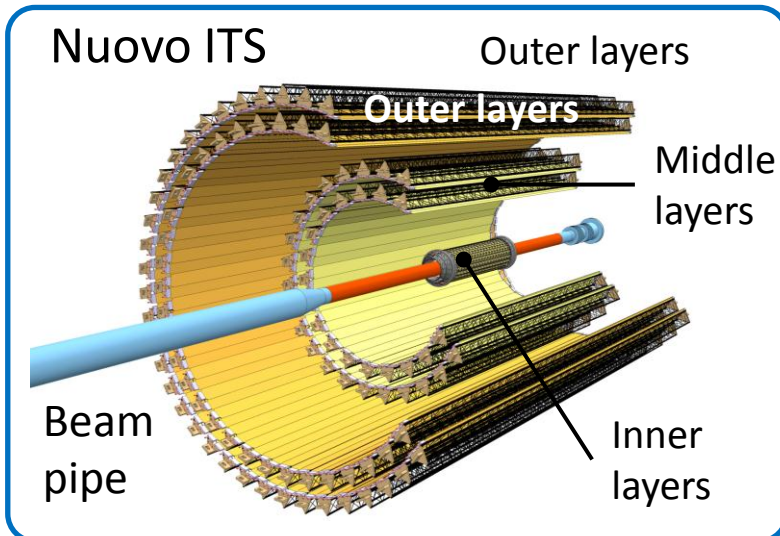
**Micro-saldatura
laser per il tracciatore
interno a pixel di
silicio dell'esperimento
ALICE ad LHC**

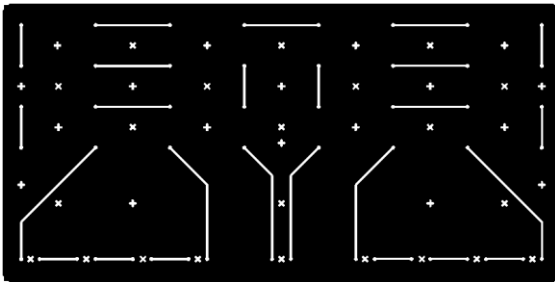


Upgrade di ALICE previsto per il LS2 (2019-2020) e comprende l'aggiornamento dell'Inner Tracking System (ITS)

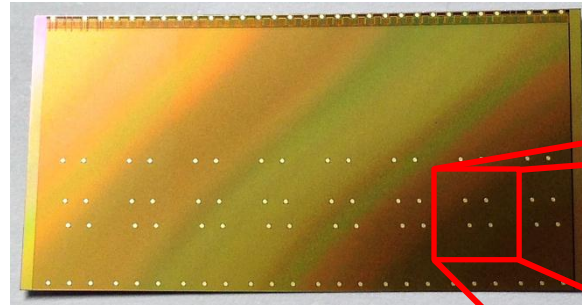


7 layers di sensori al pixel di silicio dello spessore di 50 μm

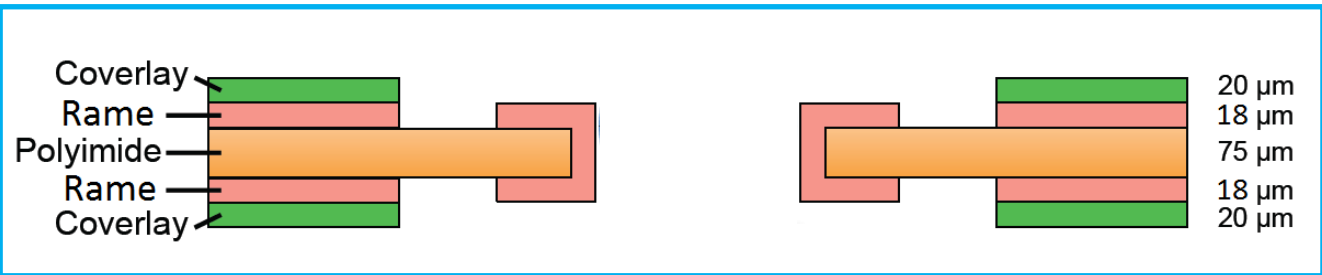
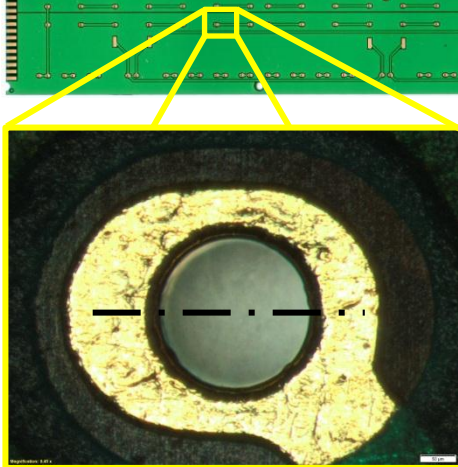
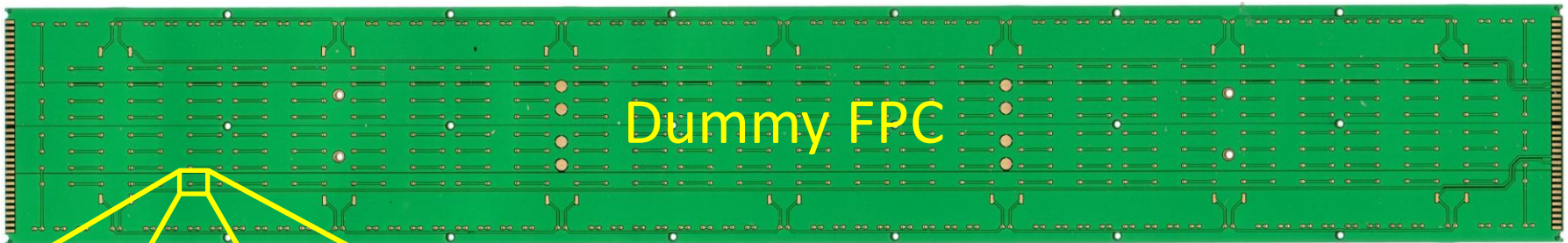
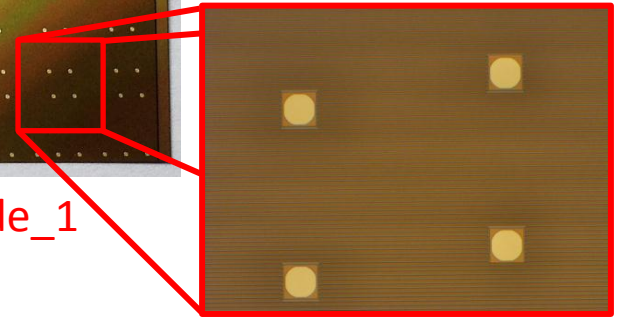


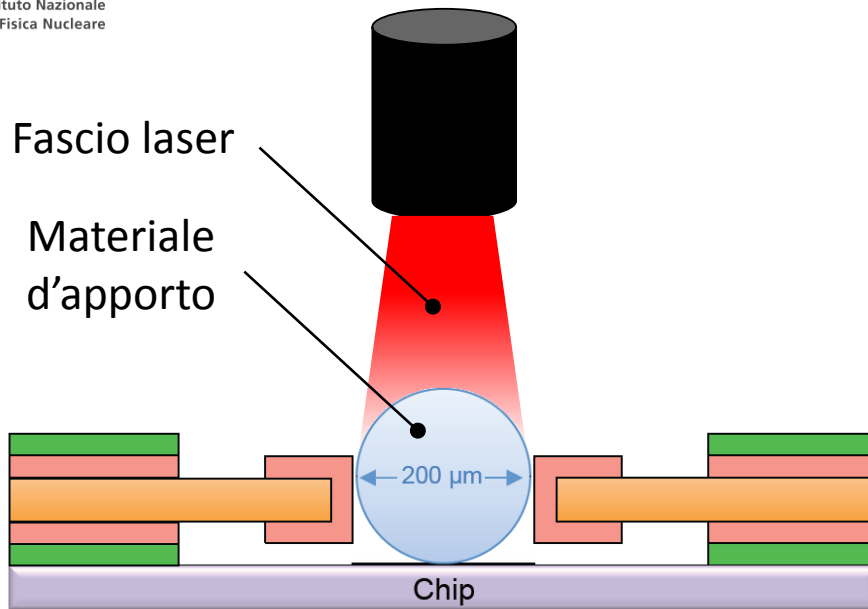


Dummy chip - 50 contacts



Real chip - pAlpide_1





Laser a diodo:

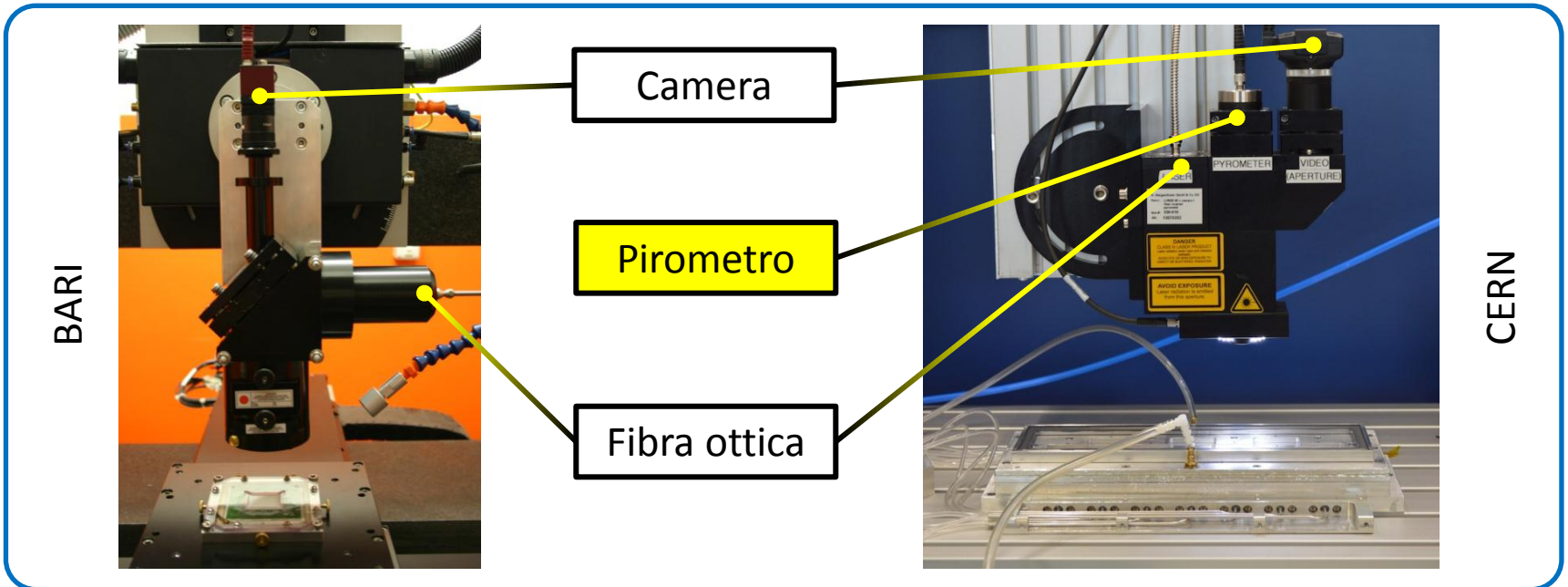
- potenza massima 25 W
- lunghezza d'onda 970 nm

Materiale d'apporto:

- micro-sfere da 200 µm
- lega saldante 96.5Sn 3.5Ag

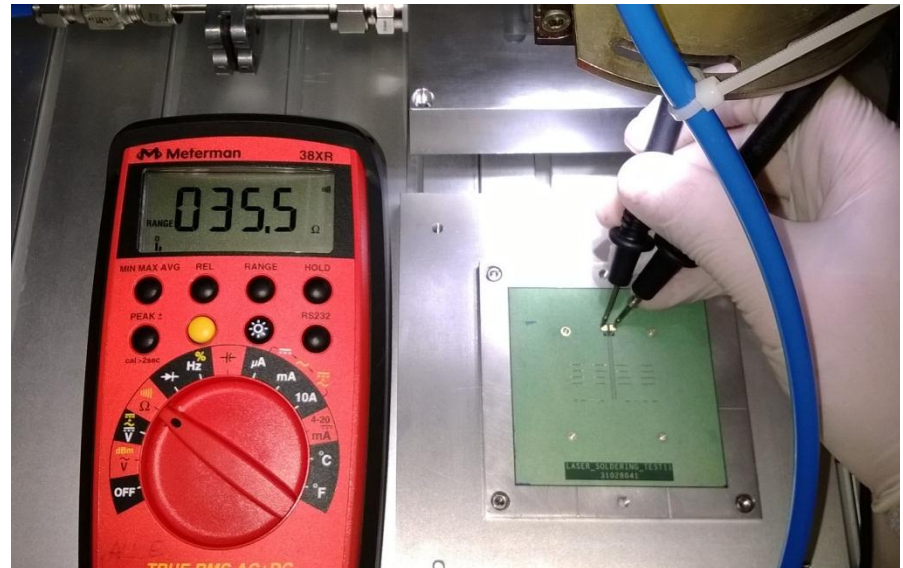
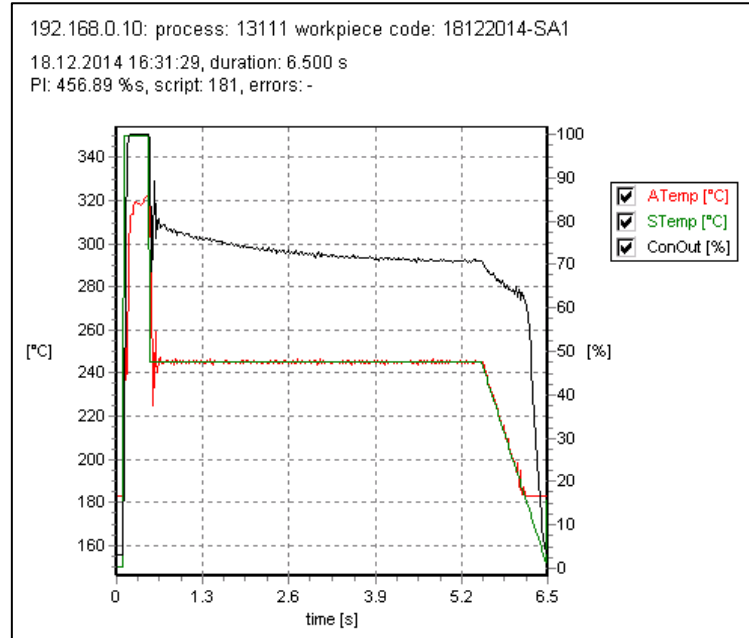
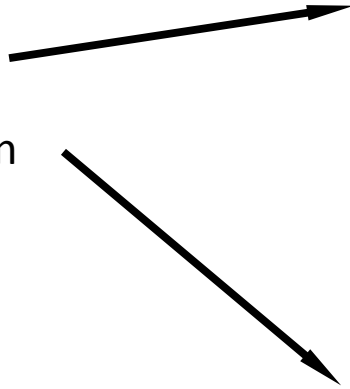
Peculiarità del processo:

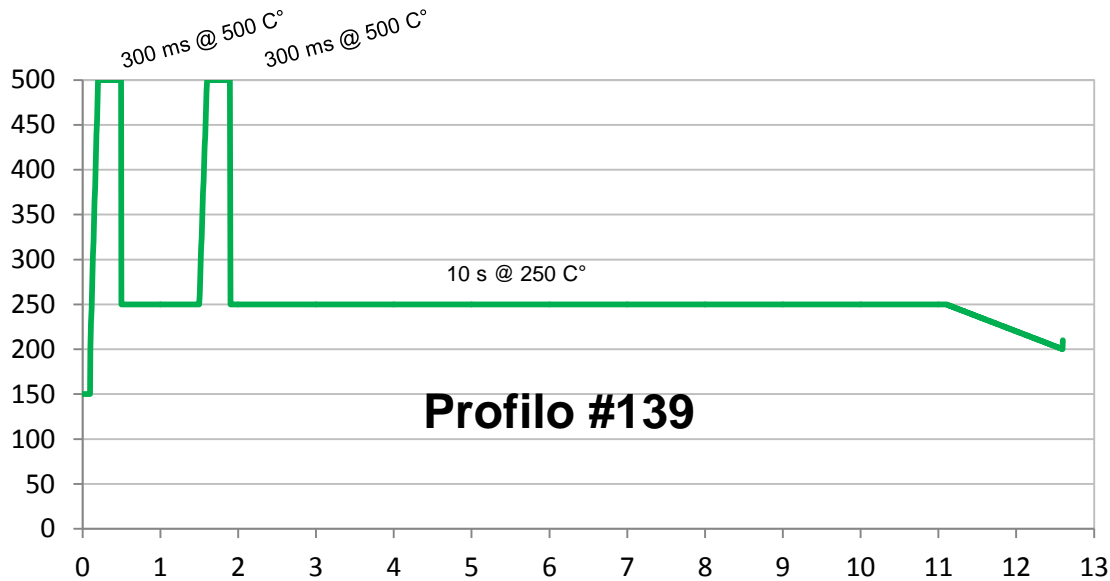
- atmosfera controllata (0.2 mbar)
- assenza di fluxante



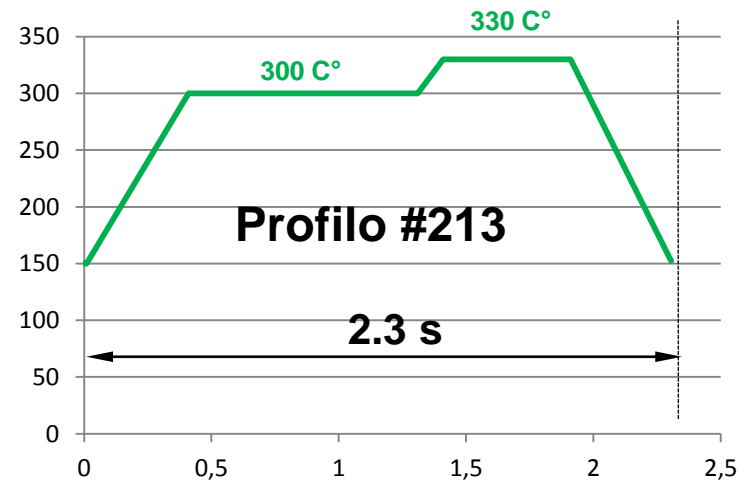
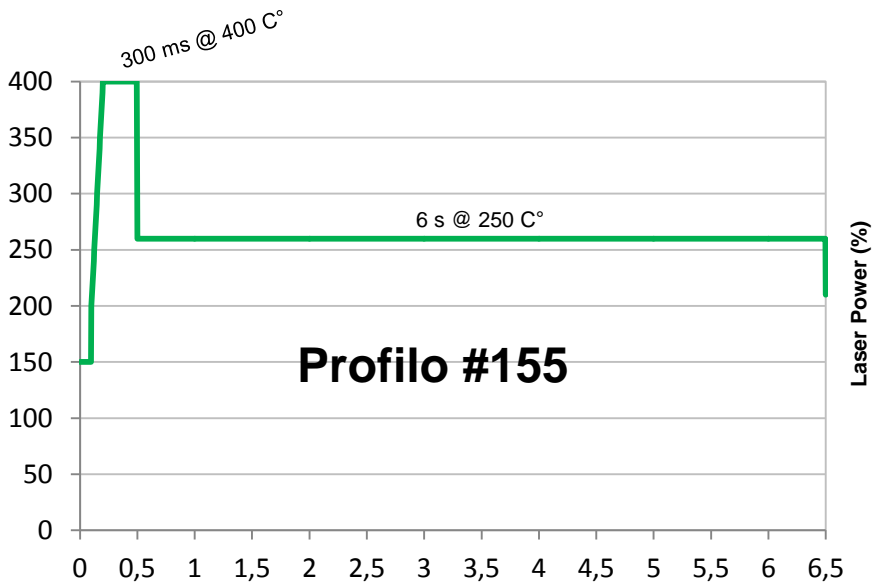
Sono stati implementate 3 modalità di controllo del processo di saldatura:

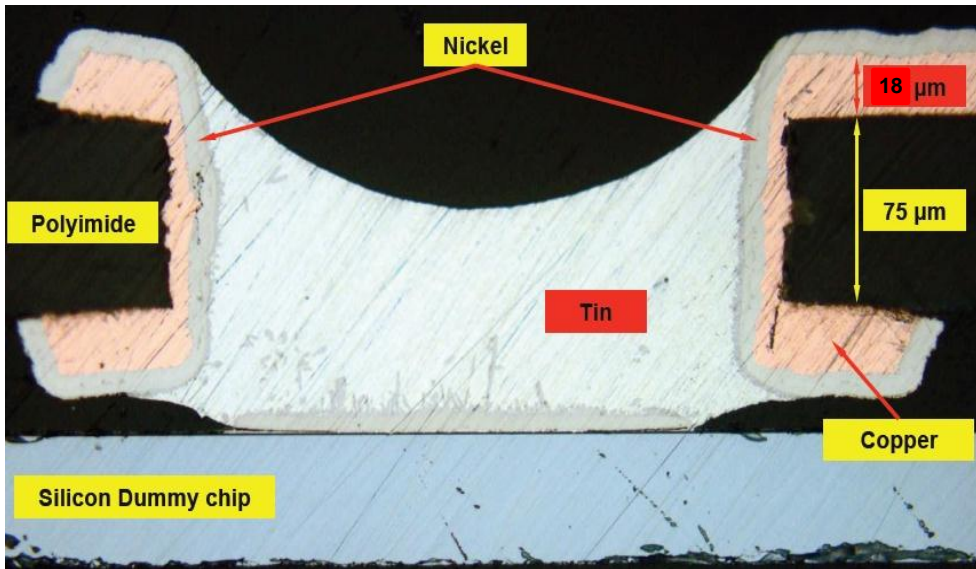
- Profili di temperatura
- Misura della daisy-chain
- Sezione micrometrica



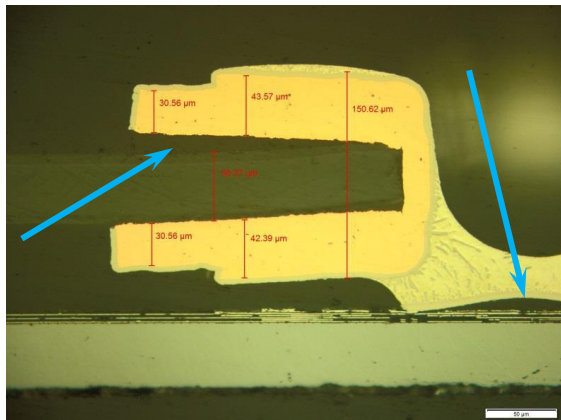


Esempi di profili di temperatura inviati al laser adottati per l'ottimizzazione del processo di saldatura

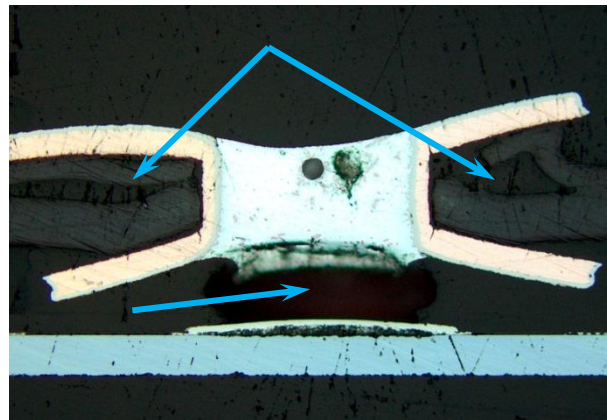




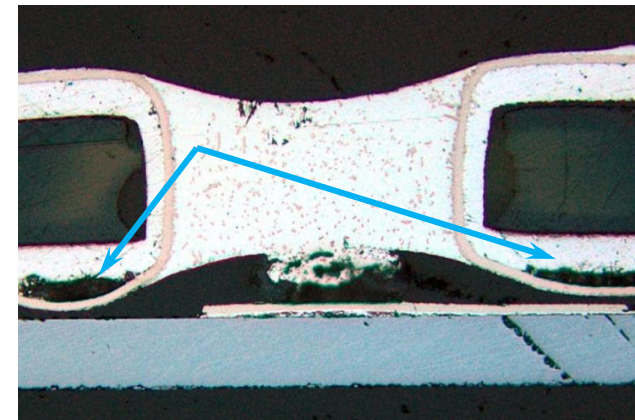
Esempio di sezione micrometrica di una connessione ottimale (ingrandimento 50x).



Quantità del materiale d'apporto insufficiente



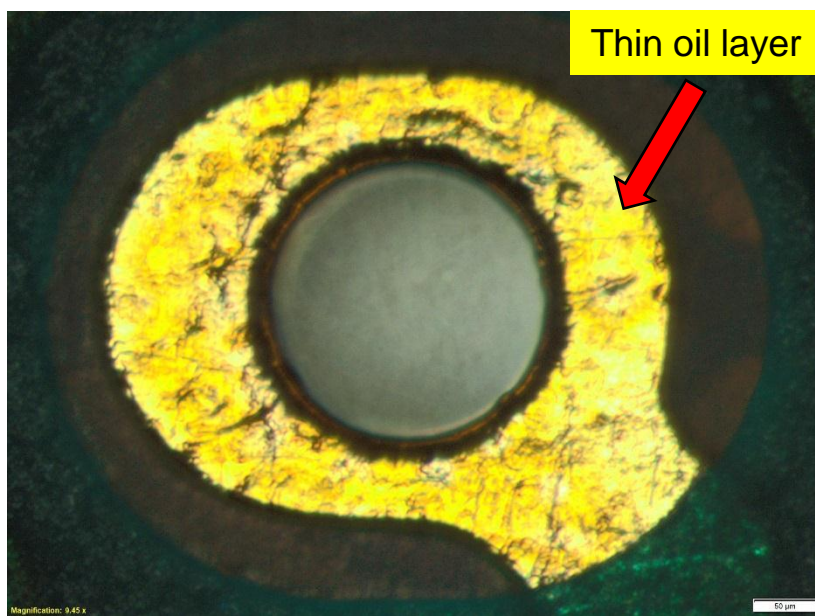
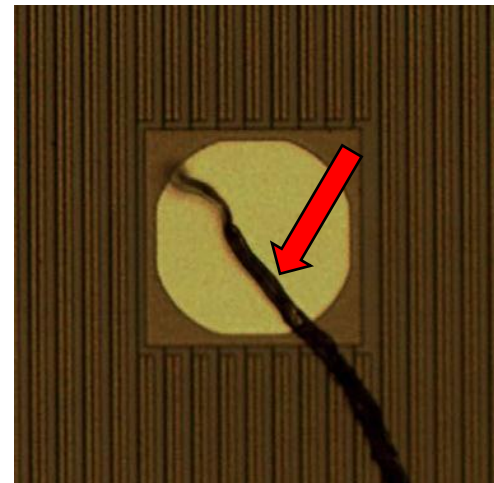
Temperature elevate durante il processo di saldatura



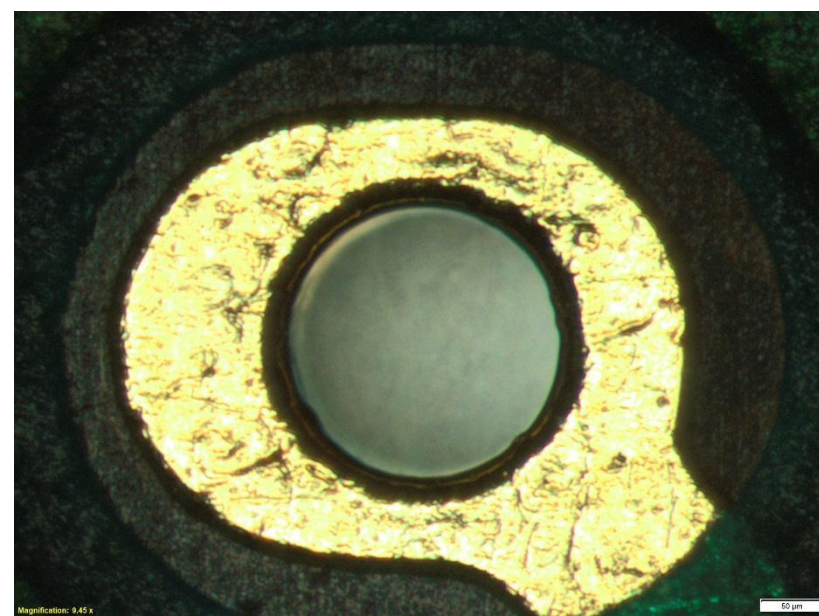
Errori durante il processo di produzione degli FPC

Impurità riscontrate su:

- superfici (e pad) dei chip
- finitura Ni/Au degli FPC



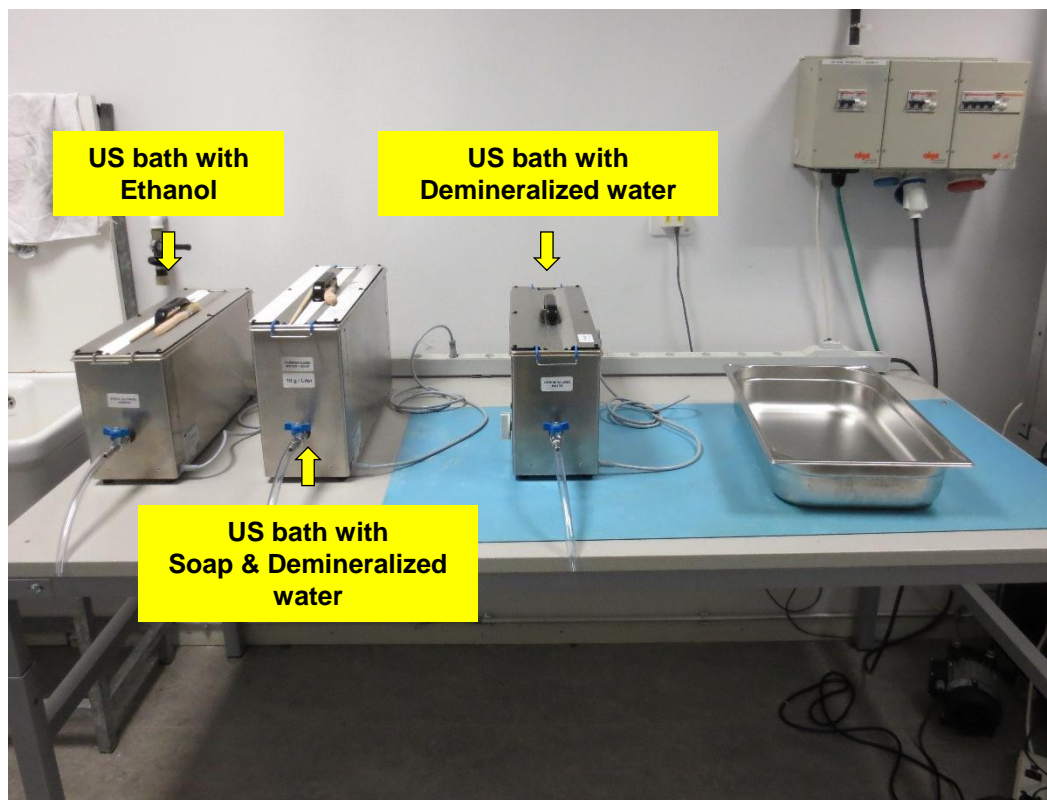
19062015-SA3-PAD-B06
Before cleaning

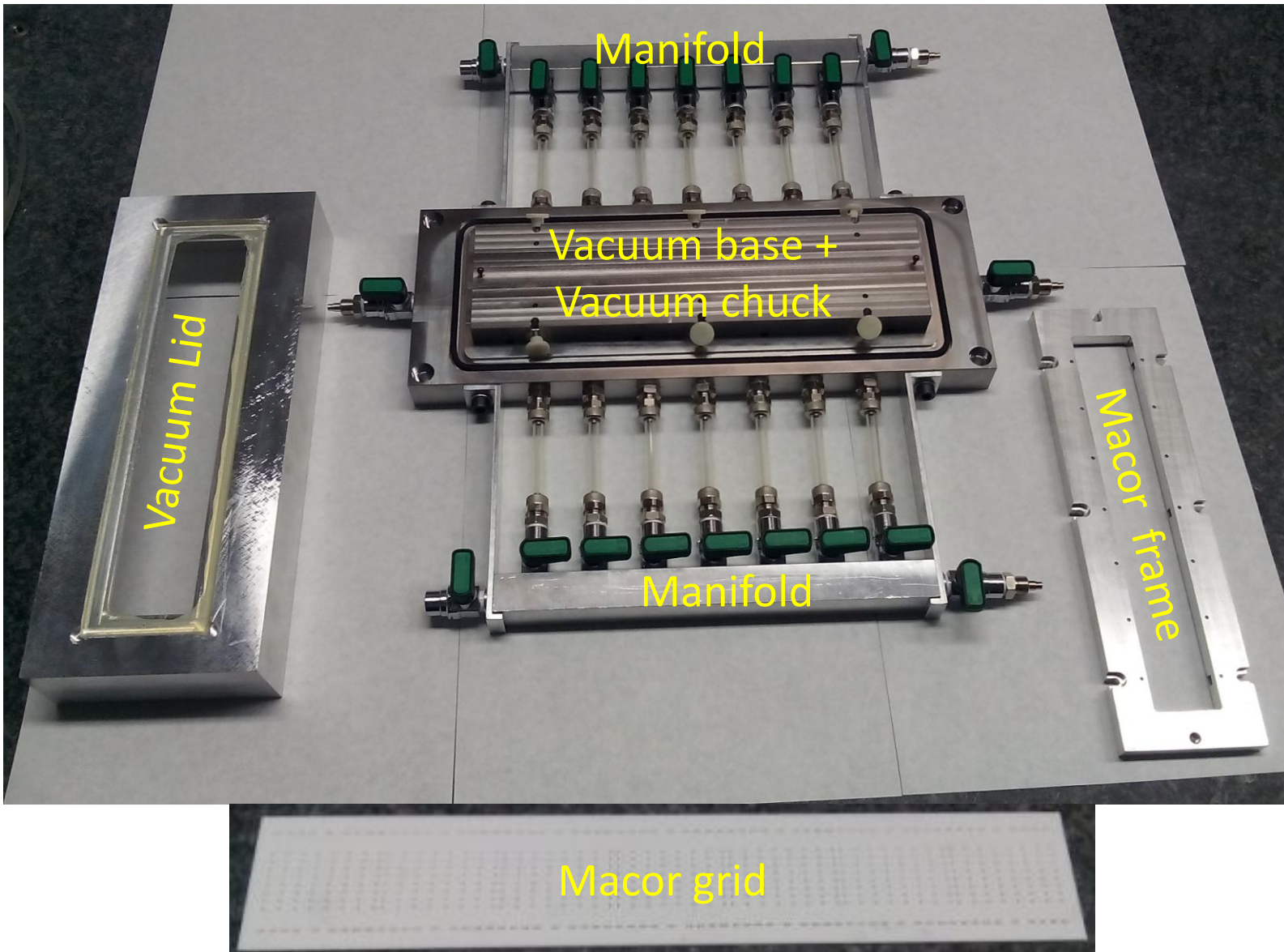


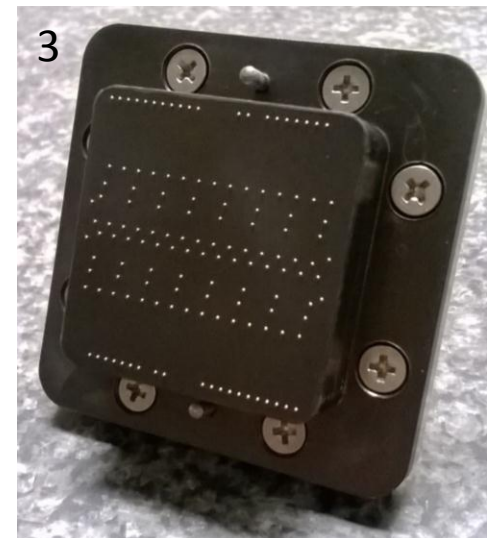
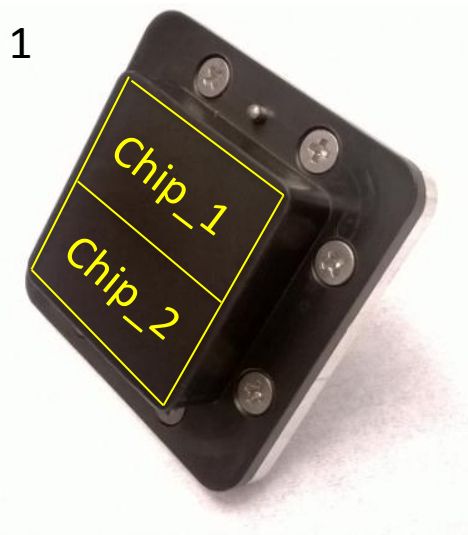
19062015-SA3-PAD-B06
After cleaning

Sistema di pulizia con vasche ad ultrasuoni dedicate:

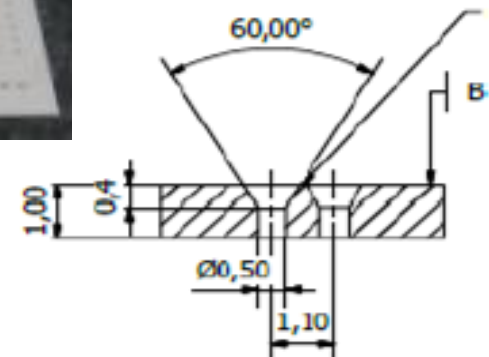
- alcool per i tool
- sapone e acqua demineralizzata per gli FPC



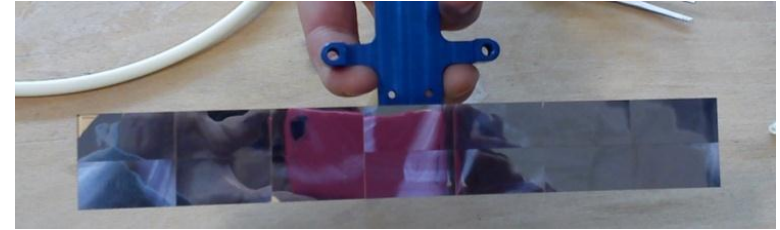
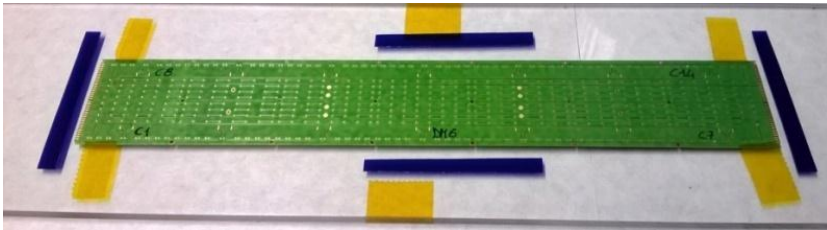




Griglia in Macor dello spessore di 1mm dotata di fori da 0.5 mm



Prototipo di modulo dummy assemblato presso il CERN

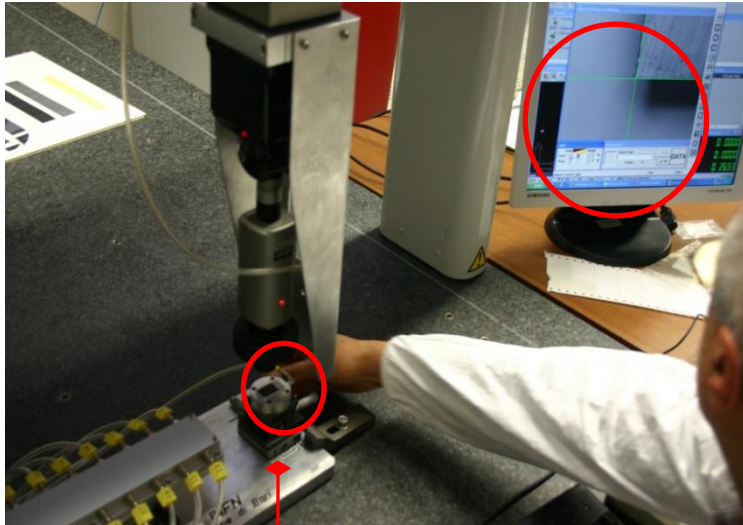


L'intera procedura di allineamento dei chip e di saldatura è stata implementata in una macchina semi-automatica che provverà, in 6 centri produttivi e a partire dal 2016, alla produzione degli oltre 2000 moduli necessari per equipaggiare l'intero nuovo tracciatore.

Grazie per l'attenzione!

Date :	10.04.2014																			
Sample name :	10042014-SA1																			
Flex name :	LASER_SOLDERING_TEST11 (12.02.14)							Polyimide thickness :			50 µm		Solder mask :		Yes					
Holes Ø	215 µm							Degas holes :		No										
Chip :	TMEC 3rd production																			
Balls Ø :	200 µm							Alloy :			Sn/Ag Box1		Gas :		No - Vacuum (90mbar)					
Row 1	PIN 1		PIN 2		PIN 3		PIN 4		PIN 5		PIN 6		PIN 7		PIN 8					
T° profile	139		139		139		139		139		139		139		139					
Process	7727		7728		7729		7730		7731		7732		7733		7734					
PI	788%		788%		712%		699%		799%		801%		884%		589%					
Row 2	PIN 9		PIN 10		PIN 11		PIN 12		PIN 13		PIN 14		PIN 15		PIN 16					
T° profile	139		139		139		139		139		139		139		139					
Process	7735		7736		7737		7738		7739		7740		7741		7742					
PI	918%		785%		770%		626%		806%		731%		753%		842%					
Row 3	PIN 17		PIN 18		PIN 19		PIN 20		PIN 21		PIN 22		PIN 23		PIN 24					
T° profile	139		139		139		139		139		139		139		139					
Process	7743		7744		7745		7746		7747		7748		7749		7750					
PI	804%		788%		810%		642%		852%		769%		624%		673%					
Row 4	PIN 25		PIN 26		PIN 27		PIN 28		PIN 29		PIN 30		PIN 31		PIN 32					
T° profile	139		139		139		139		139		139		139		139					
Process	7751		7752		7753		7754		7755		7756		7757		7758					
PI	746%		806%		729%		755%		639%		737%		867%		748%					
Row 5	PIN 33	PIN 34	PIN 35	PIN 36	PIN 37	PIN 38	PIN 39	PIN 40	PIN 41	PIN 42	PIN 43	PIN 44	PIN 45	PIN 46	PIN 47	PIN 48	PIN 49	PIN 50		
T° profile	139	139	139	139	139	139	139	139	139	139	139	139	139	139	139	139	139	139		
Process	7759	7760	7761	7762	7763	7764	7765	7766	7767	7768	7769	7770	7771	7772	7773	7774	7775	7776		
PI	773%	647%	562%	593%	822%	715%	687%	661%	864%	723%	702%	699%	753%	686%	720%	650%	673%	740%		

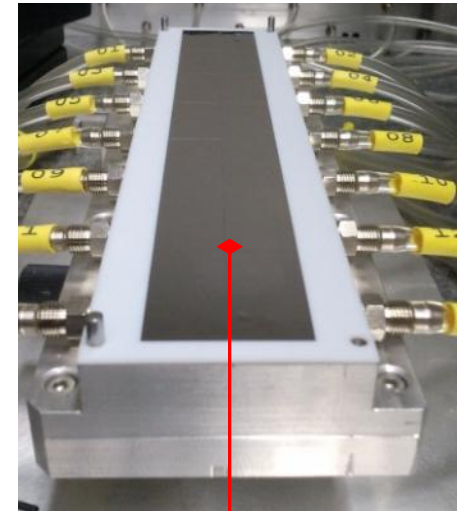
Allineamento dei chip al sistema di coordinate macchina (Mitutoyo) e successivo posizionamento tramite sistema di presa da vuoto a “ginocchio” (errore <math>< 5 \mu\text{m}</math>)



Pre-allineamento chip



presa da vuoto a
“ginocchio”



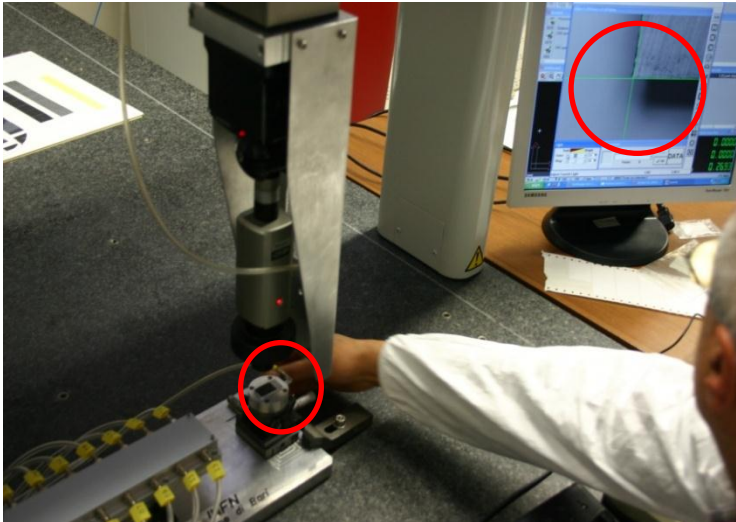
14 chip
allineati

OB module assembly table V.1

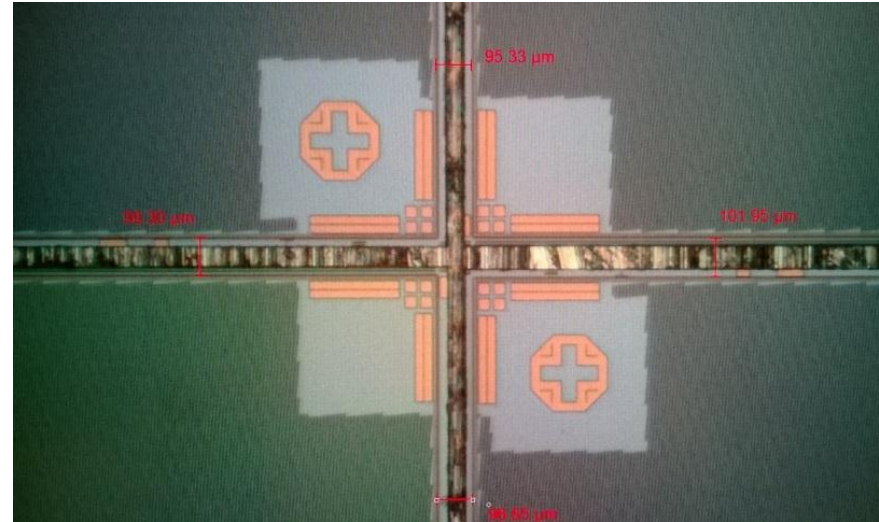


soldering ball
transfer tool in
conductive material
(Tecaform)

Preallineamento dei sensori
con macchina di misura ottica



Controllo della posizione
finale: tolleranza $\pm 5 \mu\text{m}$



Schema delle linee di collegamento tra i dummy chip allineati e l'FPC

